



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE  
(Case No. 219.005-C1)

In the Application of: **Yamada et al.**

) Group  
) Art Unit: **2825**

Serial No: **10/790,276**

)  
) Examiner:

Filed: **March 1, 2004**

)  
)

Title: **Production Managing System of Semiconductor  
Device**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

I hereby certify that this correspondence is  
being deposited with the United States  
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22313-1450 on June 25, 2004

Date

Michiko Siter  
(person signing this certificate)

Michiko Siter  
Signature

### THIRD INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Submitted herewith are two (2) sheets of a modified Form PTO-1449. A copy of  
each document cited on the attached Form PTO-1449 is also submitted.

It is respectfully requested that the Examiner make his/her consideration of these  
documents formally of record with the initial Office Action.

Respectfully submitted,



Neil A. Steinberg  
Reg. No. 34,735  
650-968-8079

Date: June 25, 2004



Sheet 1 of 2

U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE  INFORMATION DISCLOSURE STATEMENT BY APPLICANT	ATTY. DOCKET NO.	SERIAL NUMBER
	219.005-C1-US	10/790,276
	APPLICANT(S) Yamada et al.	
FILING DATE	GROUP ART UNIT	
March 1, 2004	2825	

U. S. PATENT DOCUMENTS

EXAMINER INITIALS	DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE

FOREIGN PATENT DOCUMENTS

EXAMINER INITIALS	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION YES/NO
	03-205573	9/1991	Japan			
	04-062857	2/1992	Japan			
	06-273297	9/1994	Japan			
	07-066172	3/1995	Japan			
	08-005528	1/1996	Japan			Y
	08-313244	11/1996	Japan			
	09-061142	3/1997	Japan			Y
	10-281746	10/1998	Japan			
	10-300450	11/1998	Japan			
	11-026343	1/1999	Japan			
	2000-164715	6/2000	Japan			
	2000-180143	6/2000	Japan			
	2000-124276	4/2000	Japan			
	2000-174077	6/2000	Japan			

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)


EXAMINER	DATE CONSIDERED
EXAMINER: Initial citation if reference was considered. Draw line through citation if not in conformance to MPEP 609 and not considered. Include copy of this form with next communication to applicant.	

<b>PTO-1449 (Modified)</b>  <b>U. S. DEPARTMENT OF COMMERCE</b> <b>PATENT AND TRADEMARK OFFICE</b>  <b>INFORMATION DISCLOSURE STATEMENT</b> <b>BY APPLICANT</b>	<b>ATTY. DOCKET NO.</b>	<b>SERIAL NUMBER</b>
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**OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)**

"An In-Line Contact and Via Hole Inspection Method Using Electron Beam Compensation Current", Yamada et al., IEEE 1999, Doc. No. 0-7803-5413-3/99/, available from <http://www.fabsol.com/us/images/library/21.pdf>

EXAMINER	DATE CONSIDERED
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